



#11/B  
2-2603

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q67625

SMILANSKY, Zeev, et al.

Appln. No.: 10/003,347

Group Art Unit: 2623

Confirmation No.: 6579

Examiner: Vikkram Bali

Filed: December 06, 2001

For: A PIXEL BASED MACHINE FOR PATTERNED WAFERS

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents  
Washington, D.C. 20231

RECEIVED

FEB 25 2003

Technology Center 2600

Sir:

In response to the Office Action dated November 19, 2002, within the shortened statutory period extended by one month, please amend the above-identified application as follows:

IN THE CLAIMS:

Please add the following new claims:

26. (New) A method of analyzing the surface of a semiconductor wafer comprising:  
illuminating a portion of the surface of the semiconductor wafer with light;  
detecting light scattered by the illuminated portion of the surface of said semiconductor wafer as individual pixel signatures;  
evaluating said pixel signatures according to a predetermined criterion;  
discriminating between valid and at least one of suspect and defective pixels.
27. (New) The method of claim 26 wherein a plurality of pixels is illuminated and checked concurrently.

02/27/2003 EDWARDS  
01 FC:1201